



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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AUG 11 2003
TECHNOLOGY CENTER 2800

In re the Application of:)
NISHIMOTO et al) Art Unit: 2823
Serial No.: 08/897,839) Examiner: K. Eaton
Filed: July 21, 1997)
For: STRESS-ADJUSTED INSULATING)
FILM FORMING METHOD,)
SEMICONDUCTOR DEVICE AND)
METHOD OF MANUFACTURING THE)
SAME)

RESPONSE TO OFFICE ACTION OF APRIL 7, 2003

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Responsive to the office action of April 7, 2003, please amend the captioned application
as follows: